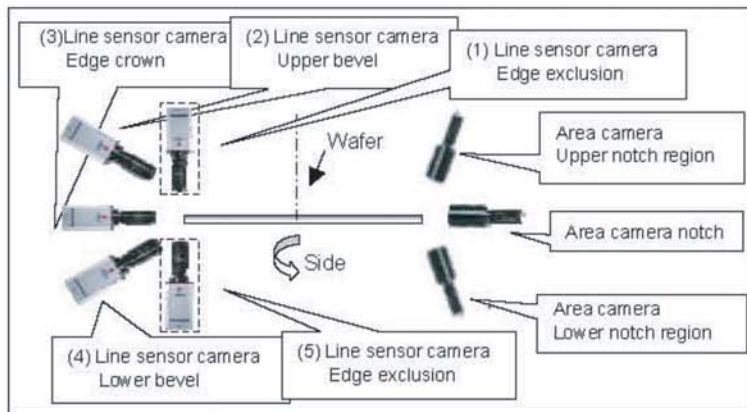


Wafer Edge Inspection Systems

WEG Series



No.1



No.2



No.3



No.4

- High Contrast Microscopic Image of Wafer captured by High Resolution Line Scan Cameras with comprehensive Defect Data Storage
- Defect Inspection and Classification by Image Data Processing
- Defect Detection Simulator Function using recorded image data
- High Throughput using High-Speed Image Data Processing Technology
- Excellent Detection Repeatability

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